



Procurement and Contracting Services

Request for Proposals an Inductively Coupled Plasma Reactive Ion Etching System (ICP-RIE)

ADDENDUM #1

**Please mark all proposal submission
Envelopes with the following information**

**Sealed RFP # L192219
Due on April 19, 2022 no later than 2:00 PM, MST**

The following questions were received prior to the close of the Technical Question period on April 6, 2022 at 12:00 PM MST:

1. Regarding the 1cm (10mm) thick sample, will this sit on a carrier or wafer not thicker than 2mm?

Yes.

2. The RFP calls out an Electrostatic Chuck – ESC. Is this a hard requirement as the RFP also specifies multiple wafer sizes from 2” – 8”. Would a multi-mechanical clamp option be acceptable? This option lends itself for handling multiple wafer sizes and pieces at the same time on a shuttle.

Yes, a mechanical clamp would be acceptable.

3. Clause 5.2.13 Delivery. Unloading, moving the system to clean room and installation are usually done by customer and we will carry out the commissioning. Please confirm whether we can exclude unloading and installation costs in our quote? We will deliver the system to the University's unloading dock.

If this is a real problem for them, then we can handle moving the system from the truck and placing it in the cleanroom. But delivery must account for the lack of a loading dock at the NFC, and it must be able to move through an 80” high x 80” wide external door. They should crate the etcher appropriately to accommodate the door dimensions.

4. Clause 5.2.13.3 Current lead time for Ion Etching System is more than 6 months due to global supply chain issue. Will our proposal still be considered if we quote longer than 6 months delivery time?

Yes.

5. Clause 5.2.13.3 Acceptance should be excluded from this delivery clause because acceptance will be carried out at the University's site, and it needs to work with the University's schedule.

University staff will be on-site and available to work with vendor to complete acceptability checks. If delay is caused due to delay on the part of the university it will not be cause for termination of purchase order.

6. Will you accept changes to the terms and conditions under section 4 of the RFP?

Vendors may submit requested changes to the terms and conditions in section 4.0, but this does not indicate acceptance of the changes by the University. The University would expect to negotiate any requested changes.

7. Section 5.2.6.2 Include six process gas regulators.

- a. Are the regulators cylinder regulators (close to or at the gas cylinders) or line regulators (close to or at the ICP etcher in the RFP)?

Cylinder regulators

- b. Will the ICP etcher in the RFP share gases with other systems in the cleanroom? Or there are gas cylinders dedicated to the system?

It will probably be a hybrid of that. Some dedicated gas cylinders and some shared with an adjacent RIE.

8. Section accessibility – Is the section not applicable for this RFP as this RFP is not for IT products.

If a software interface is part of the system then this applies.

9. Is there a preferred system delivery date other than within six months from receipt of order?

Dec 31, 2022

End of addendum, all else remains the same.